



Exceptional service in the national interest



# Advanced Fabrication Capabilities at SANDIA NATIONAL LABORATORIES

Christopher Long, Photonic & Phononic Microsystems

Sandia National Laboratories is a multimission laboratory managed and operated by National Technology and Engineering Solutions of Sandia LLC, a wholly owned subsidiary of Honeywell International Inc. for the U.S. Department of Energy's National Nuclear Security Administration under contract DE-NA0003525. SAND#####

# SILICON PHOTONICS OF THE FUTURE

## Recent research areas

- national security to everyday life
- solutions to mass-manufactured applications.

## Silicon photonics investment at Sandia

- key roles in miniaturizing complex systems
- accessing difficult-to-reach components

## Overview

- Sandia Labs MESA Complex and the NSPC
- achievements using our established Si photonics process
- recent work at in new materials and heterointegration

# MESA COMPLEX: MICROSYSTEMS ENGINEERING, SCIENCE, AND APPLICATIONS

## Charter

- design, develop, fabricate, qualify and produce at low-volume for DOE applications
- conduct leading research

DOD Defense Microelectronics Activity (DMEA) Category I A Trusted Supplier

## Resources

- 400,000 ft<sup>2</sup> complex
- >650 employees
- secure facilities (TA-1 limited area)

## Dual fab facility

- silicon CMOS fab
- general purpose Micro Fab

## Products

- ASICs, III-V ICs, MEMS, FPAs, RFICs, optoelectronics



Center for Integrated  
Nanotechnologies



# MESA's FABS: CO-LOCATED PRODUCTION AND R&D



Clean room area 34,500 ft<sup>2</sup> (11,900 ft<sup>2</sup> Class 1)

23 laminar flow clean bays

3.3V 350nm SOI Rad Hard CMOS (CMOS7) in production

3.3/1.8V 180nm SOI Rad Hard CMOS (CMOS8) in development

Supplier of custom Rad-Hard ICs for life extension programs

DOD Defense Microelectronics Activity (DMEA) Category 1A Trusted Supplier for design, fab, and test

Micro-Electro-Mechanical System (MEMS)

Custom Technologies: Ion Traps, Silicon Photonics, AlN Resonators

Clean room area 30,400 ft<sup>2</sup> (14,900 ft<sup>2</sup> Class 10/100)

6 Class 100 clean bays and 20 Class 10 clean bays

Reconfigurable tools from wafer pieces to 6" wafers

III-V compound semiconductor epitaxial growth and circuit fabrication

Gallium Arsenide & Indium Phosphide HBT production

Breadth of III/V materials

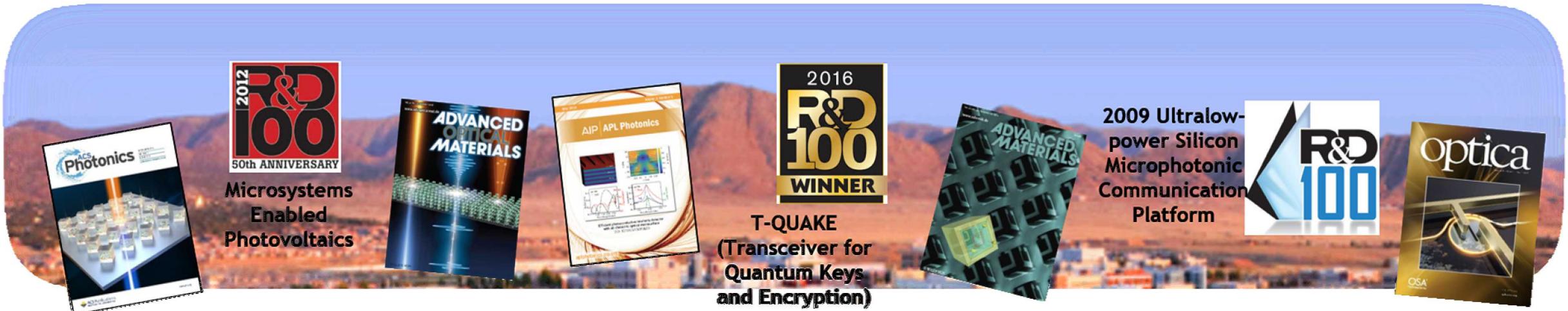
Optoelectronics, VCSELs, and photo diodes

3D Packaging & Heterogeneous Integration Post-processing hybridization

# SANDIA'S NATIONAL SECURITY PHOTONICS CENTER

Serve the nation as a center of excellence for national security photonics through scientific excellence and innovations and leading-edge integrated photonics solutions

- >60 photonics staff (plus postdocs and students) with expertise in device design, modeling, simulation, epitaxy, device fabrication, integration, assembly, and test
- partnership with government agencies, industry, and universities
- technology transfer to industry
- areas of interests: communication, sensing, computing, imaging, quantum applications
- [www.sandia.gov/mesa/nspc](http://www.sandia.gov/mesa/nspc)

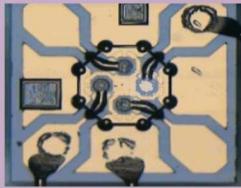


# EXTENSIVE INTEGRATED PHOTONICS RESEARCH

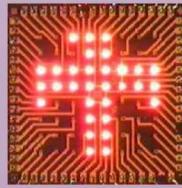
## Advanced photonics R&D: design, model, fab, package, and test

Materials: Silicon, III-V (Phosphides, Arsenides, Antimonides, Nitrides), Lithium Niobate, Graphene, etc.

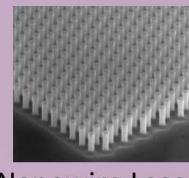
### Sources



Single-frequency tunable VCSELs



High efficiency VCSELs



Nanowire Laser



High power GaAs laser

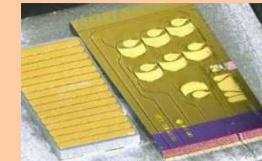
### Control / Manipulation



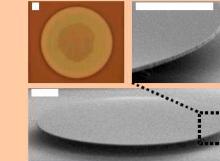
Resonant optical modulator/filter



Array waveguide grating channelizing filter

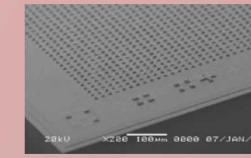


RF channelizing filter

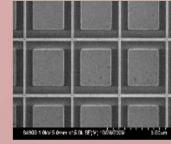


LiNbO<sub>3</sub> Freq. converter

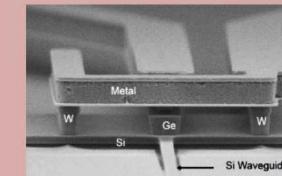
### Detection



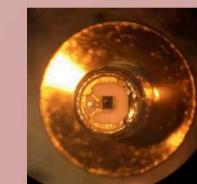
Mid-IR detector



Plasmonic perfect absorber

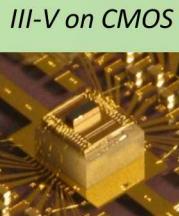


Germanium detector on silicon

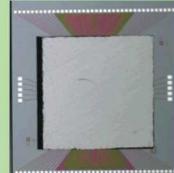


X-ray detector

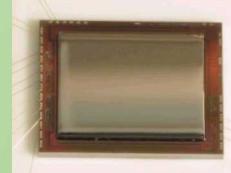
### CMOS Integration



III-V on CMOS



CMOS on Si Photronics

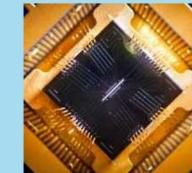


nBn on CMOS

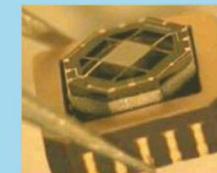
High-speed optical transceivers

IR Focal Plane Array w/ ROIC

### Chip-scaled MicroSystems



Quantum surface ion trap



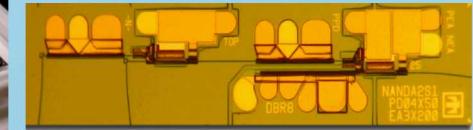
Atomic clock



Quantum Key Distribution transceiver



Photovoltaics w/ microlenses



High-speed all-optical logic

# SILICON PHOTONICS CAPABILITY

## Overview

- 10 years of development
- leverages existing CMOS infrastructure
- 200 mm SOI wafers with 3um BOX
- two waveguide layers: Si and SiN
- selective area epitaxy for Ge detectors

## Passive devices

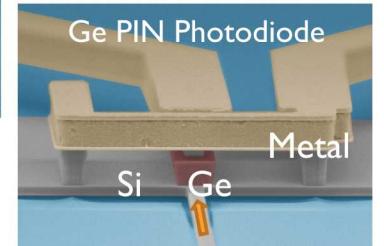
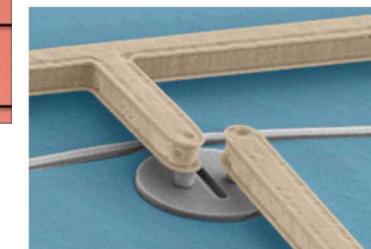
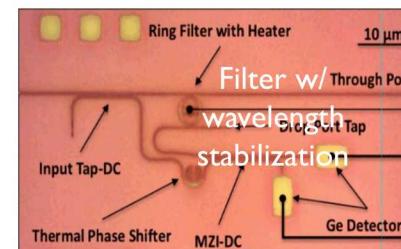
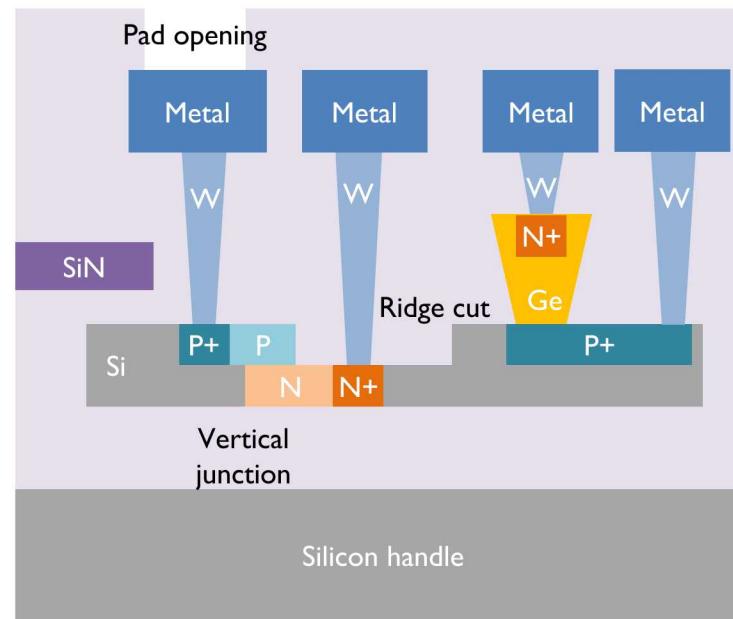
- Si rib and ridge-type waveguides
- ring filters
- grating couplers (1D and 2D)
- waveguide crossings
- splitters (amplitude and polarization)

## Active devices

- microdisk and MZ modulators
- thermal and EO phase shifters
- Ge PIN and APDs

## Demonstrated circuits

- quantum cryptography (DV and CV QKD)
- RF processors (channelizer, SSB modulators)
- data links in harsh environments



# PROCESS FLEXIBILITY

Wafer bonding: III/V and other materials

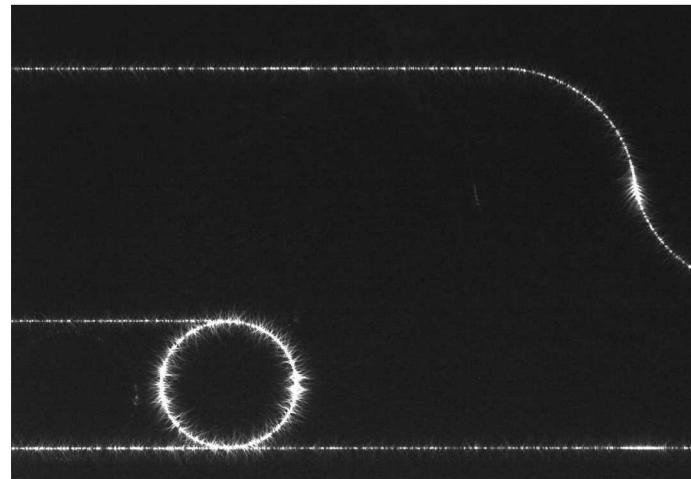
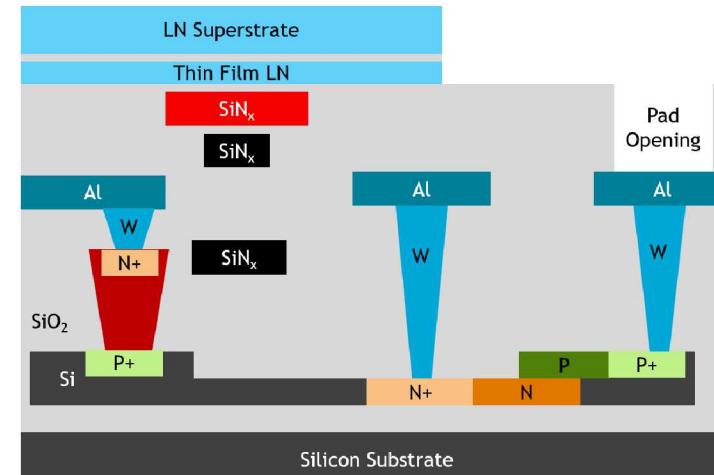
Extra waveguide layers for transitions

Multi-mask exposures with low stitching errors

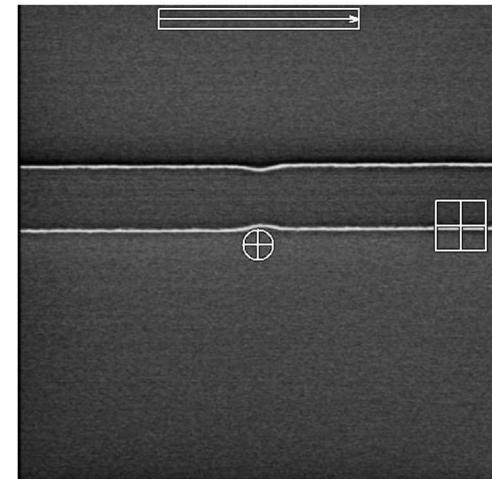
Mix and match standard litho with e-beam

Alternative waveguides:  $\text{Al}_2\text{O}_3$  and AlN

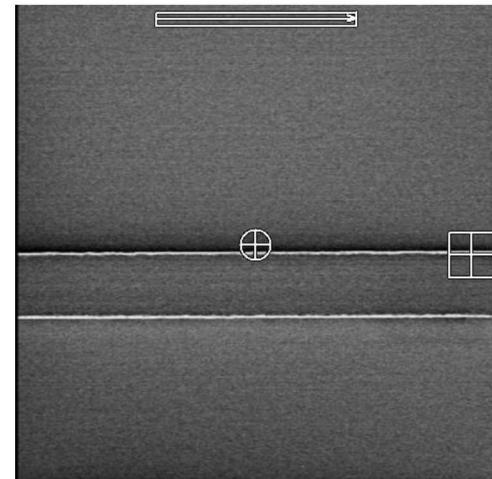
Optical MEMS demonstrations



Alumina waveguides for visible light photonics



Images of waveguides crossing between reticles. Proper mask design eliminates stitching errors and ensures low optical loss.



# INP PIC CAPABILITY

## Overview

- 20 years of development
- multiple band edges via quantum well intermixing and regrowth steps
- ridge, buried and deep etch waveguides
- top side n- and p-type contacts

## Passive devices

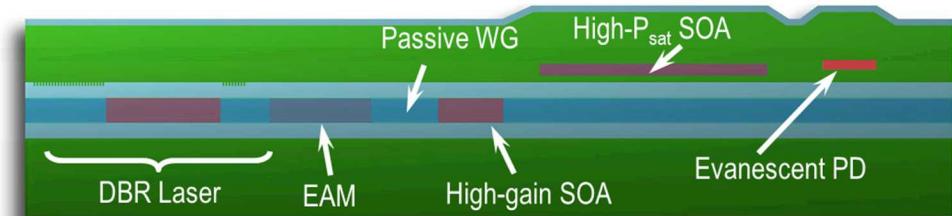
- arrayed waveguide gratings
- ring resonators
- TIR mirrors
- resistors and capacitors

## Active devices

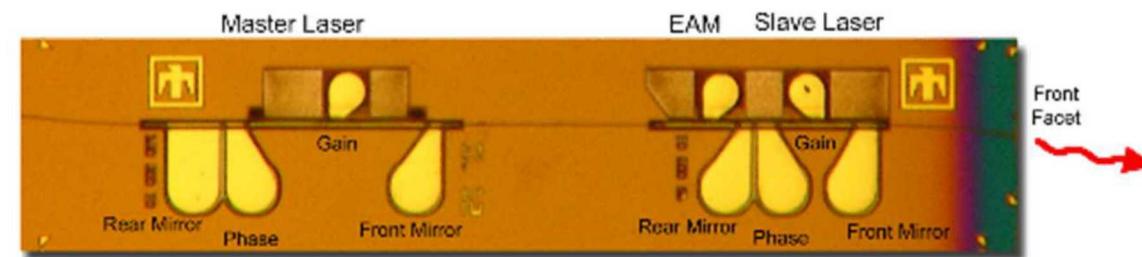
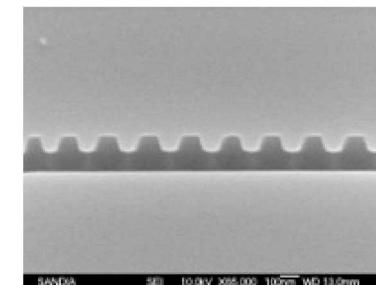
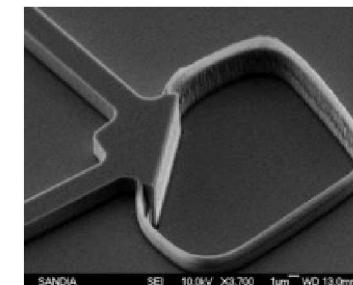
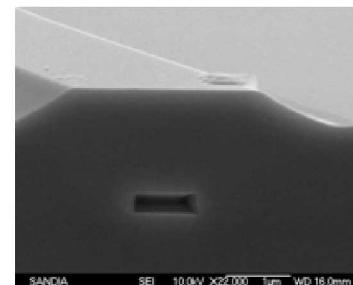
- lasers (DBR, DFB, etc.)
- modulators (EAM and MZ)
- SOAs (high-gain and high-power)
- photodetectors (evanescently coupled and QW)

## Demonstrated circuits

- optical logic ages
- data links
- coupled-cavity lasers

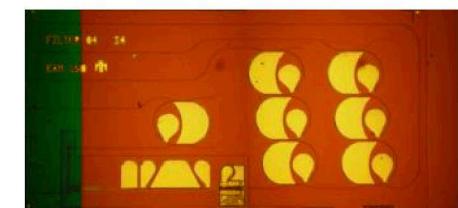


Device cross-section



On-Chip Injection Locking  
Enhanced Modulation > 50 GHz, C-Band

RF-Optical Channelizing Filter  
1-20 GHz RF on C-Band Light



# COLLABORATIVE MULTI-PROJECT WAFERS

**Goal:** collaborate with customers to develop novel processes and solutions to support project and application requirements, **not** to compete with US commercial foundries

- collaborative and custom work
- academia, industry, other government entities

## Silicon photonics

- three deliverables: passive, active, and active+Ge
- typical block size: 4mm x 26 mm
- design manual
- libraries available through Synopsis

## InP PICs

- designs accepted until 9/2019
- multiple tiers/process flows available

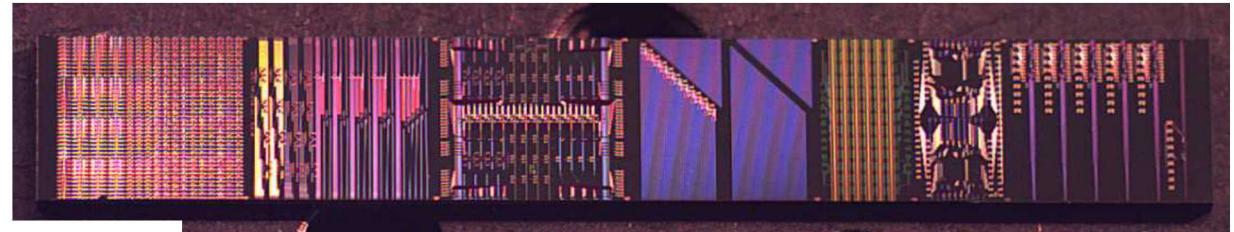


Image of MPW run, supporting Columbia, U of AZ, UC Berkeley, UCSD & Caltech

### 4. TECHNOLOGY OVERVIEW

Sandia National Laboratories (SNL) has developed a Microsystems and Engineering Sciences Applications (MESA) facility located in a limited classified area. Trusted custom fabrication of silicon and radiation-hardened process technologies for digital, analog and mixed signal ICs is currently available through MESA, which delivers production micro-electronics components to support special DOE and DOD programs. The MESA Complex is designed to integrate the numerous scientific disciplines necessary to produce functional, robust, integrated **microsystems** and represents the center of SNL's investment in **microsystems** research, development, and prototyping activities. This suite of facilities encompasses approximately 400,000 square feet and includes **cleanroom** facilities, laboratories and offices.

More recently, a silicon photonics process (SPP1) has been engineered and matured in the MESA facility, a cross section of which can be seen in Figure 4-1. The silicon photonics process is an electro-optical silicon photonic integrated circuit platform built on silicon on insulator (SOI) wafer technology. Included within SPP1 are two waveguide interconnect layers one in crystalline silicon, the other in deposited silicon nitride, a full suite of dopant implants to provide active p-n junction formation and low resistance **ohmic** contacts, aluminum metal interconnect layer(s), and selective epitaxial growth of Germanium with optional n and p type implants all surrounded by optical cladding layers. SNL's silicon photonics process represents a mature process technology upon which to develop high performance integrated circuits and systems. The SPP1 has enabled numerous best in class device demonstrations, including ultra low energy optical modulators [4], high speed, low capacitance Si photodiodes [5], high speed optical modulators [6] and the resonant frequency locking of **micro-ring** resonator filters [7] and modulators [8].

### 5. BASELINE PROCESS DETAILS

The details of the base process flow are described in Table 5-1. The base process can be broken down into three subsets:

#### SNL Silicon Photonics Design Manual

For more information:  
[photonics@sandia.gov](mailto:photonics@sandia.gov)

	Process	Tier 1	Tier 2	Tier 3
	Description	One MOCVD regrowth	Two MOCVD regrowths	Full custom process
Lasers	Tunable (~5 nm)	YES	YES	YES
	Tunable (~40 nm)	YES	YES	YES
SOA	High Gain (dB/cm)	400	400	400
	High $P_{sat}$	NO	YES	YES
Detectors	$R$ (A/W)	0.8	0.8	0.8
	$P_{in}$ saturation (dBm)	15	15	15
Wave-guide	Bandwidth (GHz)	> 20	> 40	> 40
	Propagation Loss (dB/cm)	< 2	< 2	< 2
EA-Modulator	Turning mirror loss (dB)	N/A	< 0.5	< 0.5
	Length (μm)	125	125	125
MZ-Modulator	Efficiency (dB/V/cm)	800	800	800
	Loss (dB)	< 1	< 1	< 1
Phase Modulator	Bandwidth (GHz)	> 20	40	40
	Electrode Length (μm)	250	250	250
	Efficiency ( $V_n$ )	2	2	2
	Loss (dB)	~1	~1	~1
	Bandwidth (GHz)	> 20	> 20	> 40
	Length (μm)	200	200	200
	Efficiency (°/V)	20	20	20
	Loss (dB)	< 1	< 1	< 1
	Bandwidth (GHz)	> 20	> 20	> 40

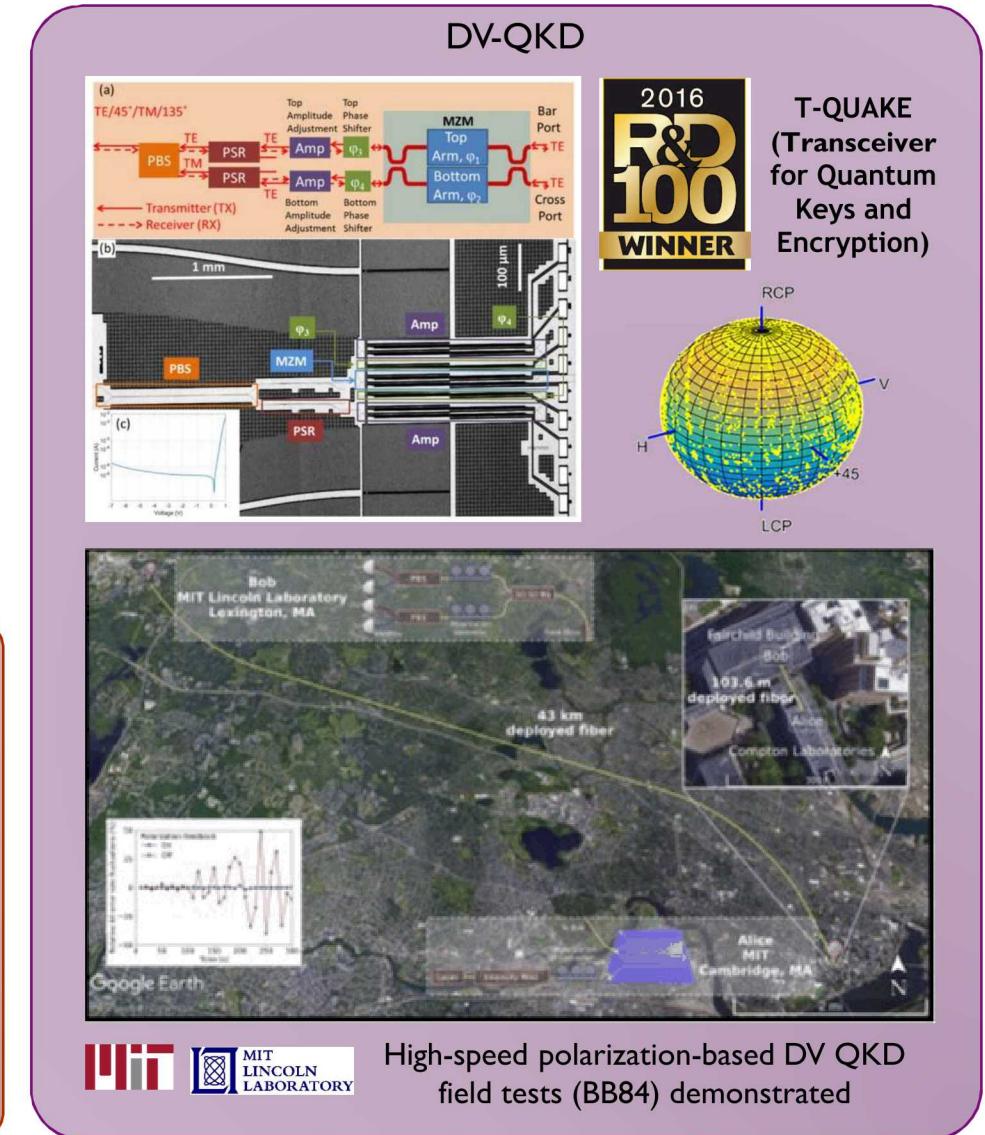
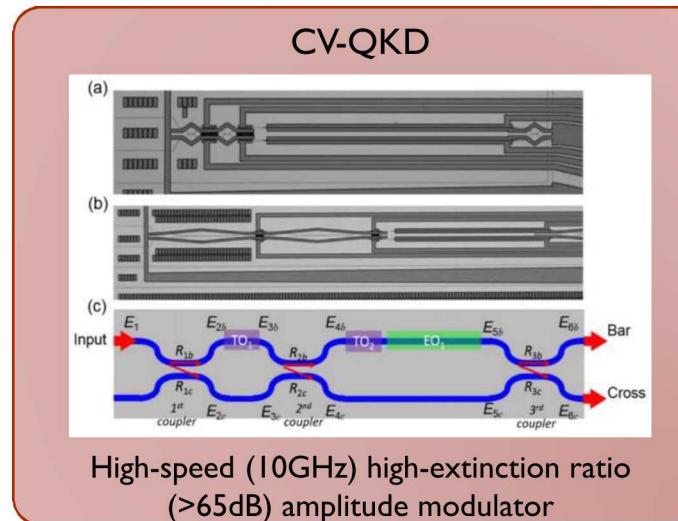
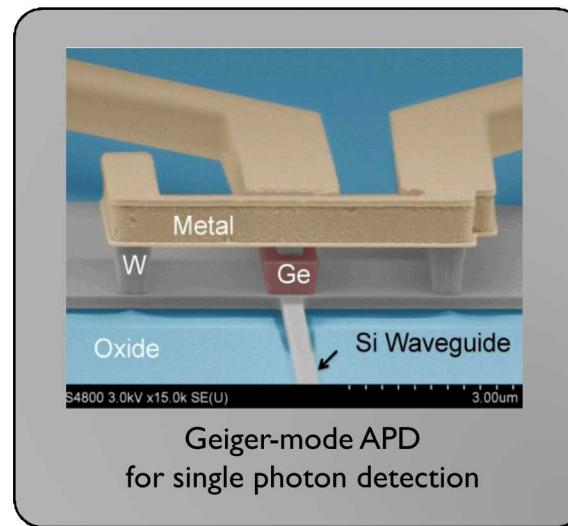
# INTEGRATED SI PHOTONICS FOR QUANTUM COMMUNICATION

Internally funded programs to develop quantum comms

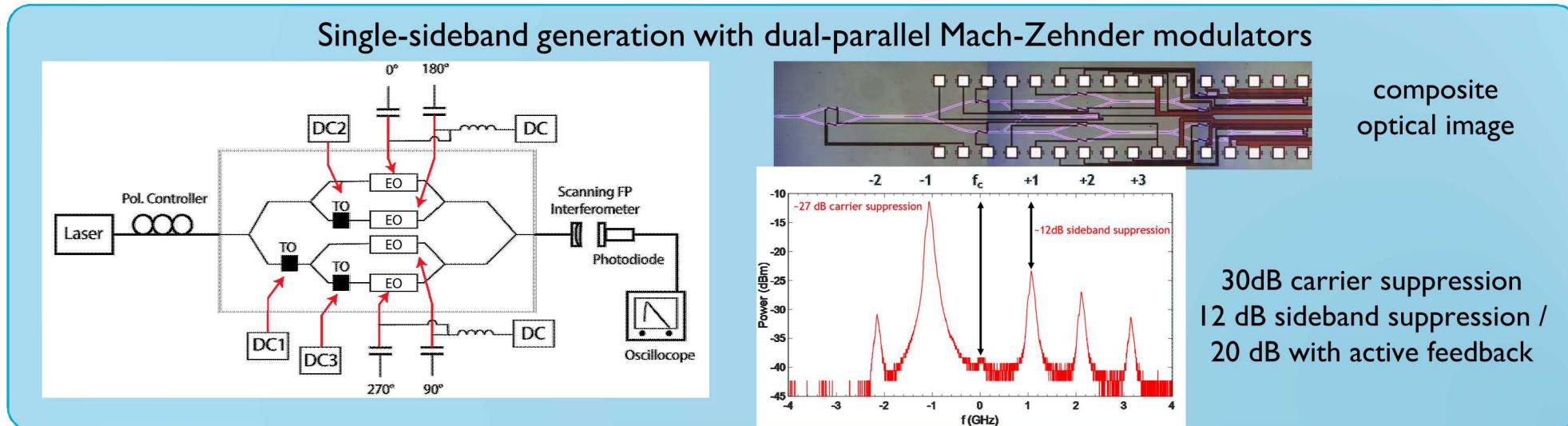
Many foundational building blocks for advancing quantum science developed

- detectors
- modulators
- frequency converters
- amplifiers
- optical transceivers

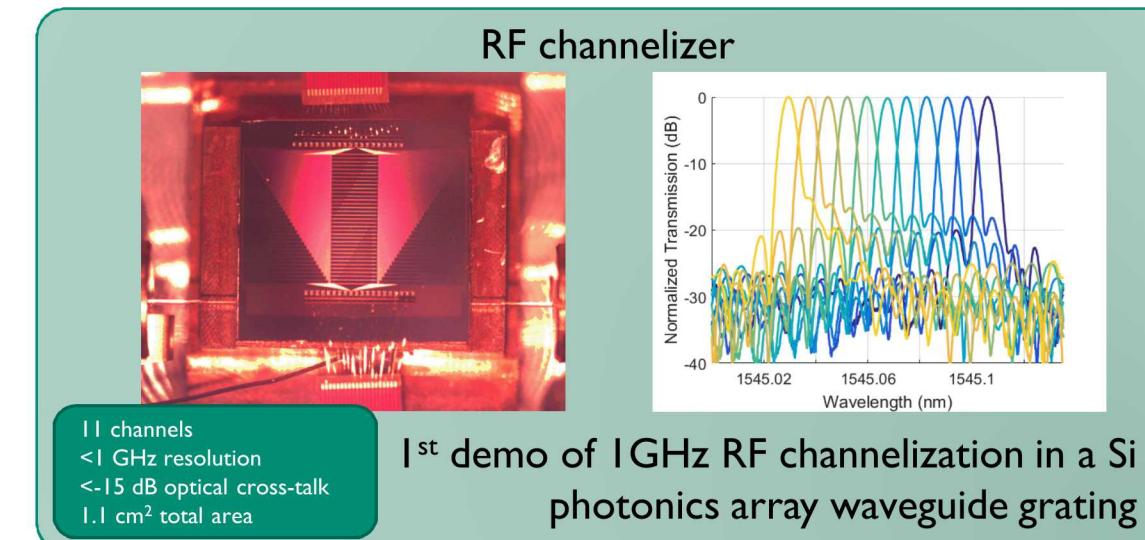
Demonstration of DV-QKD across 43km link with key generation rates  $>100$  kbps



# INTEGRATED SI PHOTONICS FOR RF SIGNALS

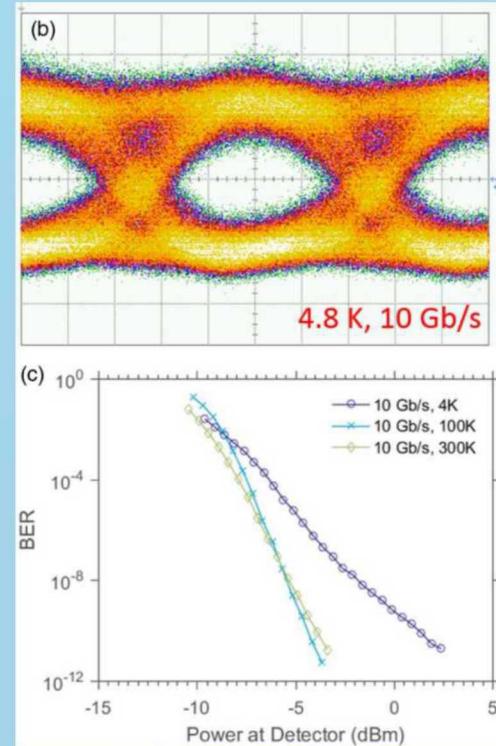
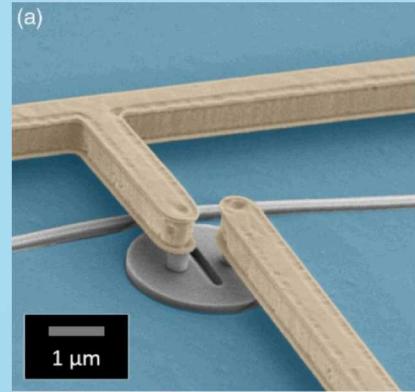


CLEO 2019



Photonic processing of RF signals provides significant reduction in SWAP-C for high frequency applications (>40 GHz).

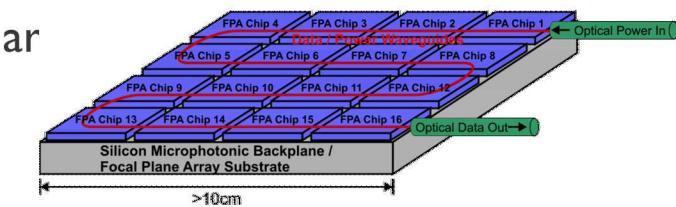
# PROCESS FLOW OPTIMIZATION: CRYOGENIC DATA LINKS



High-speed low-power resonant modulator operating at cryogenic temperatures ( 50K, 4K, and below)

## Applications

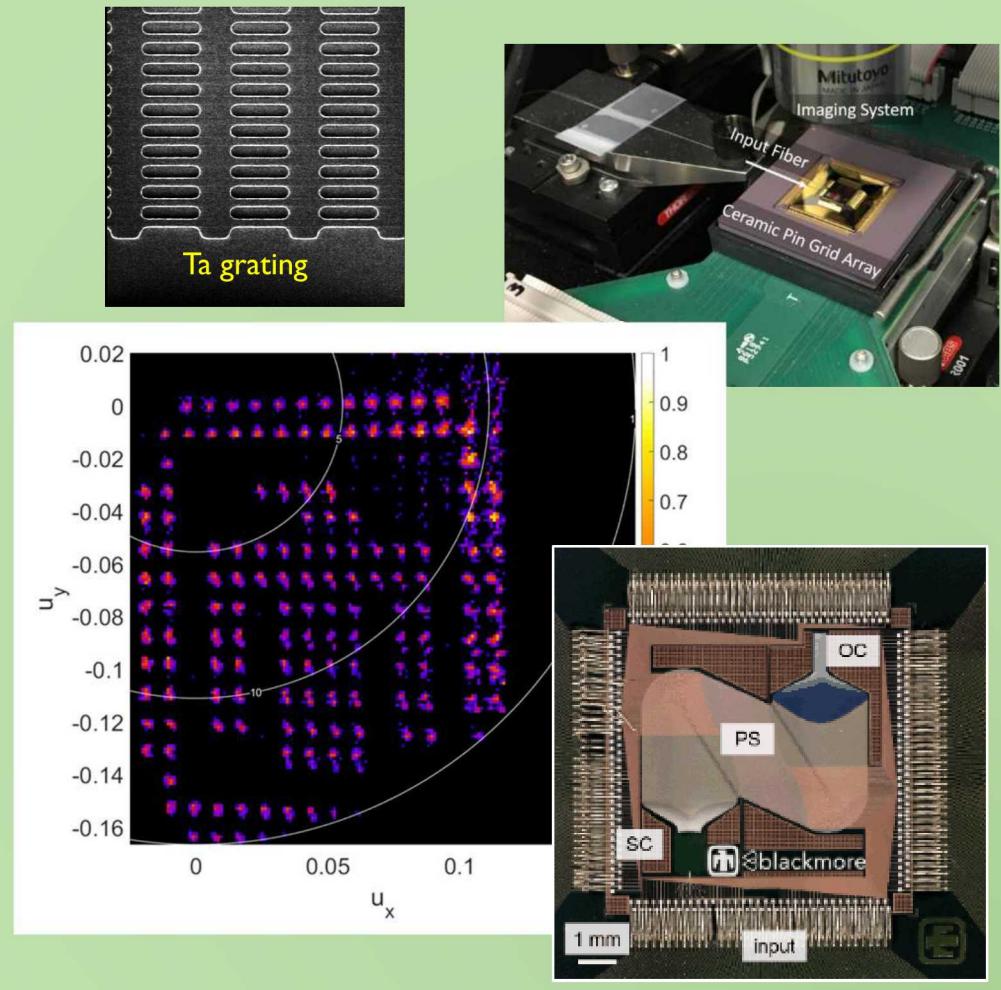
- superconducting computing
- optical backplane for focal plane ar
- quantum system interface



## Succinct summary

- increased doping concentrations prevent freeze out
- 10Gbps operation at 4.8K
- RC time constant limited error-free operation

# MONOLITHIC INTEGRATION: CHIP-SCALE OPTICAL BEAM STEERING



Phase Optimization of Si Photonics 2D  
Electro-optic Phased Array  
CLEO 2019 & Optics Express 21(4), 5198-5208, 2013

## 2D silicon photonic optical beam scanner

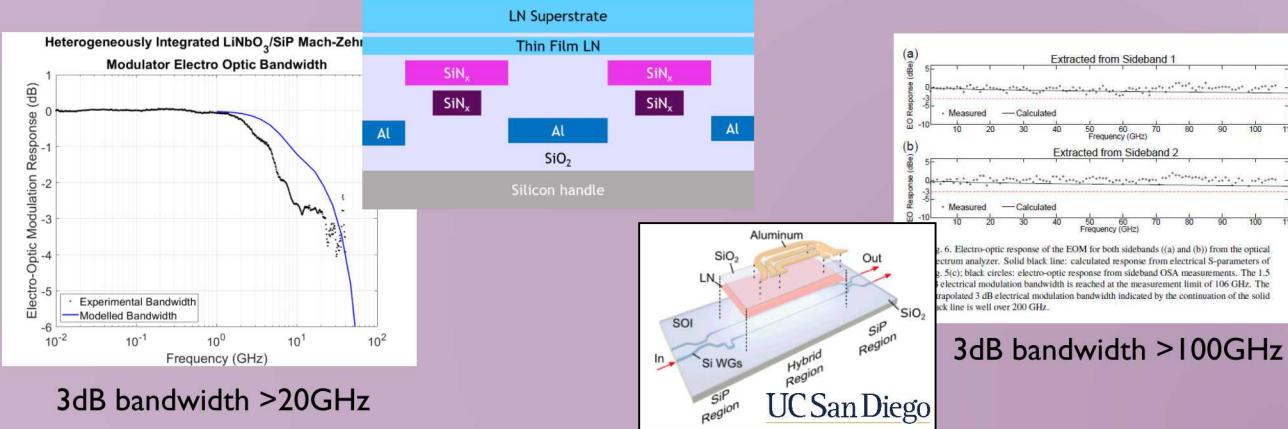
- huge push for integrated solutions
- small output couplers desired → high index contrast materials
- developed CMOS-compatible process in Ta

## Results

- electronic (low-power EO phase shifter) and wavelength steering
- field of view:  $24^\circ \times 10^\circ$ ; divergence angle:  $0.3^\circ \times 0.3^\circ$
- 256 independent channels with 3- $\mu\text{m}$  pitch
- area:  $750\mu\text{m} \times 750\mu\text{m}$  with high fill factor
- electronic packaging with interposer and chip carrier

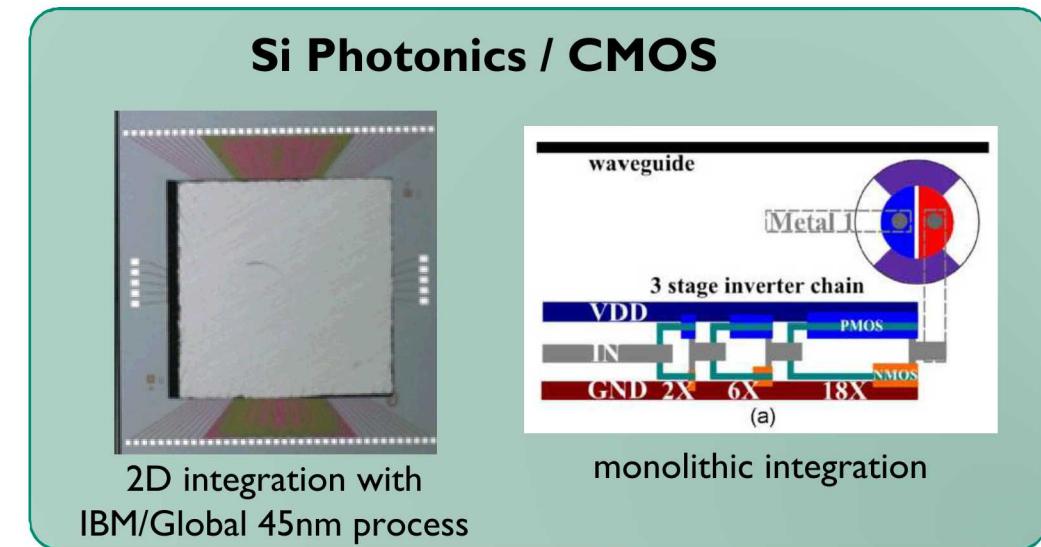
# HETEROGENEOUS INTEGRATION

## Si Photonics / Lithium Niobate



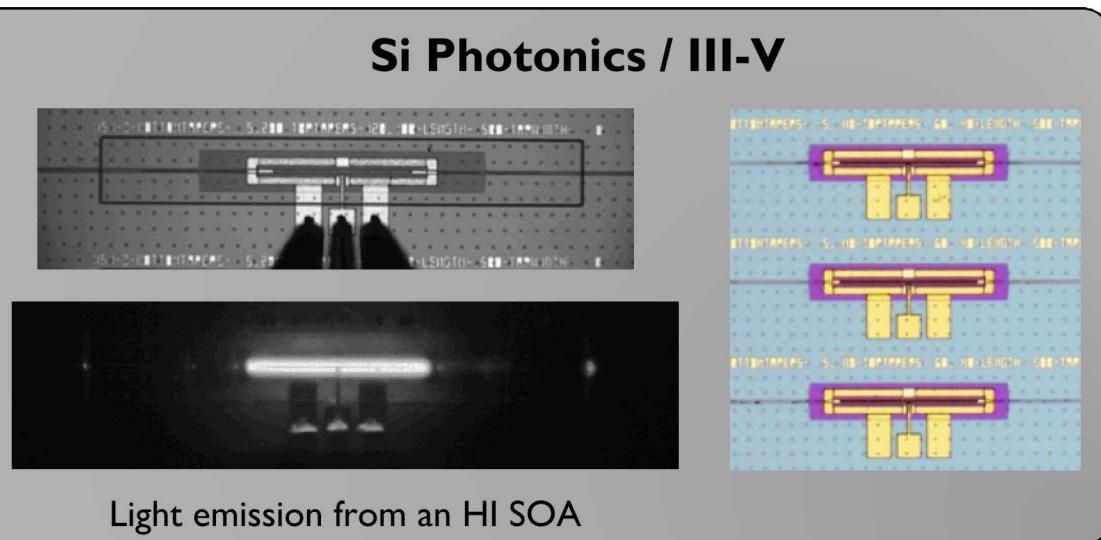
OIC2019 & Optics Express 26 (18), 23728-23739, 2018

## Si Photonics / CMOS



IEEE Aerospace 2015 & IEEE Photonics 4(1), 242-249, 2012

## Si Photonics / III-V



Heterogeneous integration enables miniaturization with independent material and device optimization

- integration of  $\text{LiNbO}_3$  and III-V Lasers on silicon photonics
- non-traditional materials such as Epsilon-Near-Zero  $\text{In}_2\text{O}_3$  and  $\text{CdO}$ , graphene
- integration of CMOS with silicon photonics,  $\text{InGaAsP}/\text{InP}$ ,  $\text{InGaAs}/\text{GaAs}$ , and other materials

# SANDIA NATIONAL SECURITY PHOTONICS CENTER

## Distinguishing capabilities

- flexible process flows and materials
- co-located design, fab, packaging and test facilities

## Non-traditional application spaces

## Si photonics and optoelectronics

## DOD Defense Microelectronics Activity (DMEA) Category I A Trusted Supplier

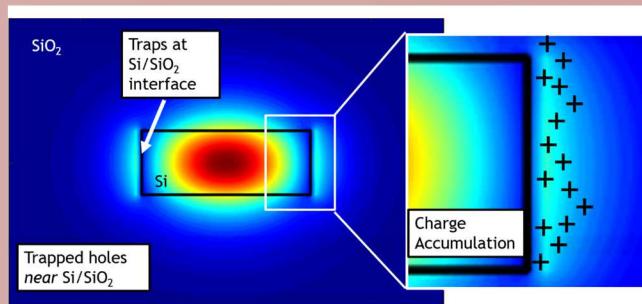
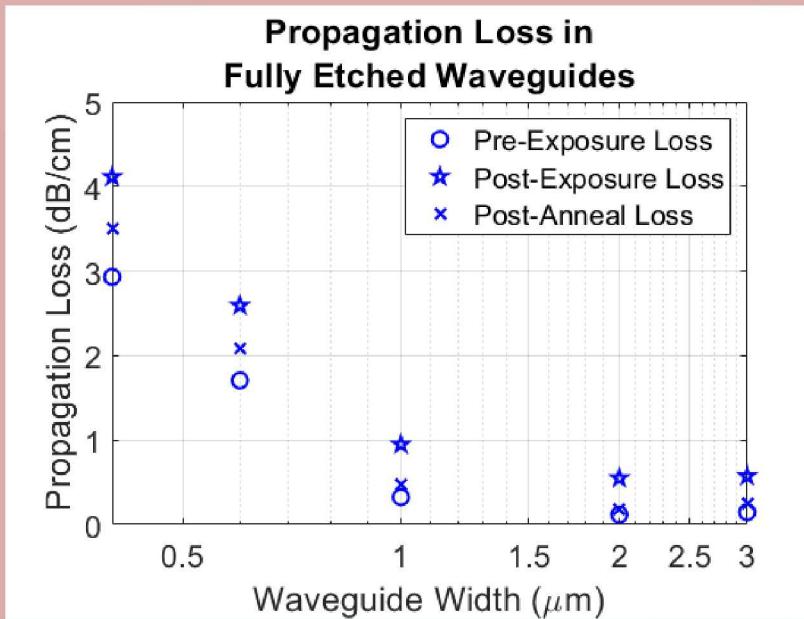
For more information:  
[photronics@sandia.gov](mailto:photronics@sandia.gov)



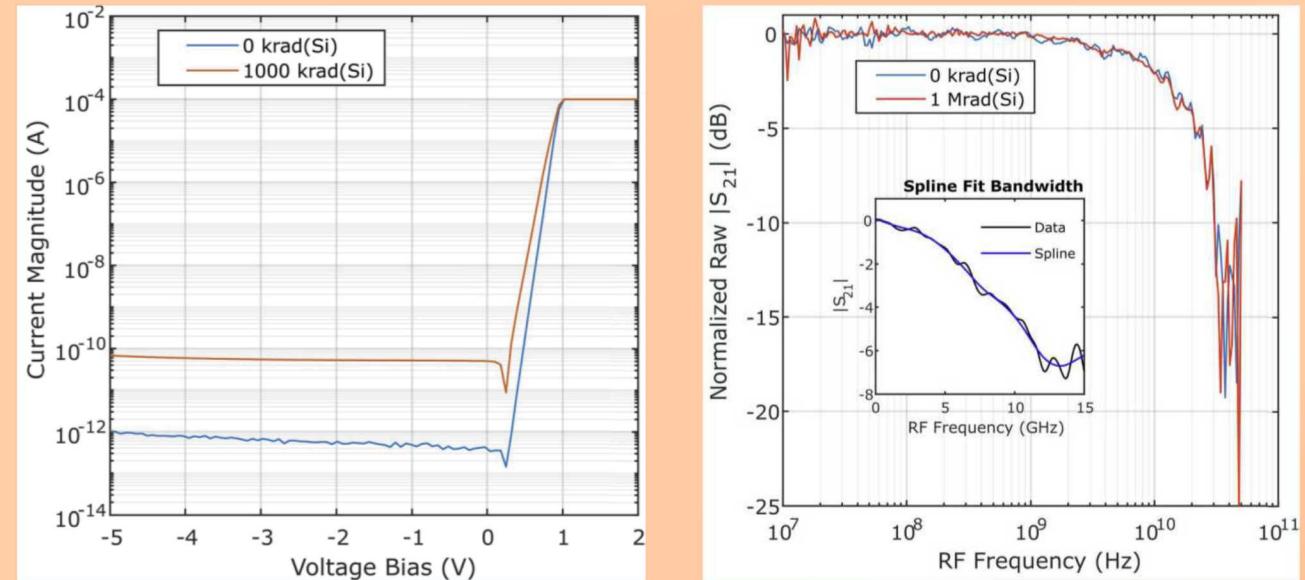
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## BACK UP SLIDES

## SI PHOTONICS IN HARSH ENVIRONMENTS: GAMMA RADIATION



Waveguides show small increase in loss due to increased free carrier density. Partial recovery with heat anneal.

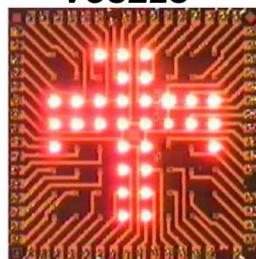
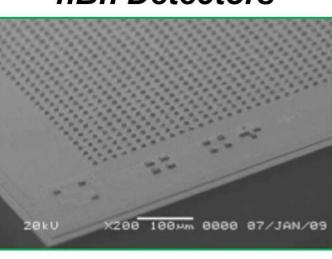
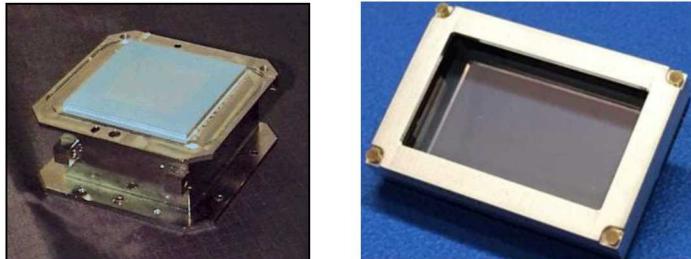
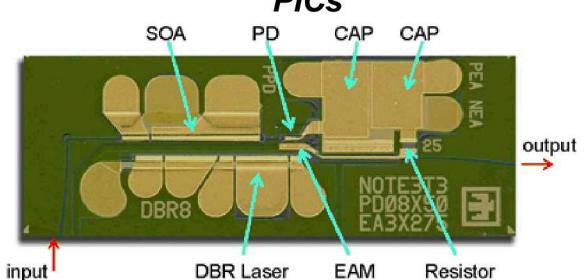
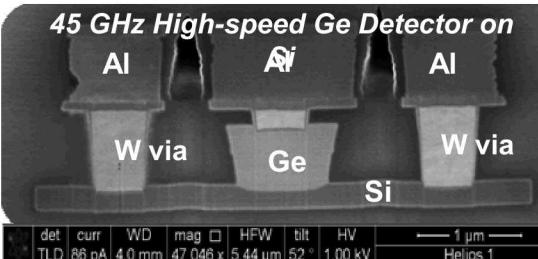
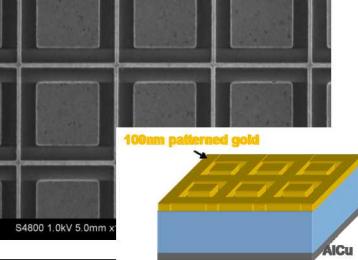
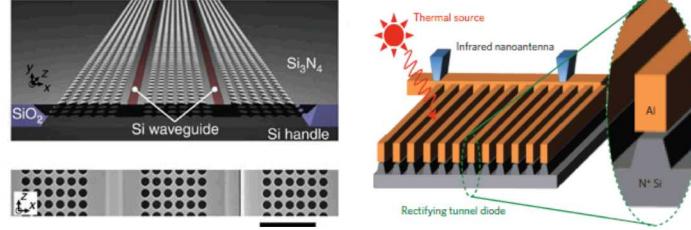
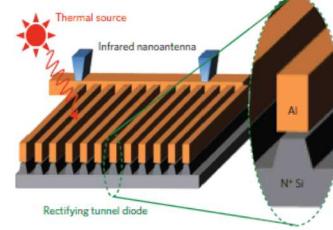


Modulators (and detectors) show increased dark current, but negligible decrease in bandwidth.

Boynton, et al., "Propagation loss in crystalline silicon photonic waveguides due to gamma radiation," GOMAC Tech, 2019

Hoffman, et al., "The Effect of Gamma Radiation Exposure on Active Silicon Photonic Device Performance Metrics," *IEEE Trans. Nuclear Sci.*, 66(5), 801, 2019

# SANDIA'S PHOTONICS "TOOLKIT"

	Compound Semiconductors	Silicon
Surface Normal	<b>VCSELS</b>  <b><i>nBn Detectors</i></b> 	<b><i>Custom Si Detectors</i></b> 
Waveguide	<b>PICs</b> 	<b>Si photonics</b> 
Nanophotonics	<b>Nanoantennae FPAs</b> 	<b>Nano-optomechanics</b>  <b>Rectennae</b> 

## SILICON PHOTONICS OF THE FUTURE

Silicon photonics will play key roles in miniaturizing complex systems and accessing difficult-to-reach components. Recent research spans a wide breadth of topics, from national security to everyday life, and niche solutions to mass-manufactured applications.

Achieving these goals requires a multi-disciplinary facility, with the dedication to reproduce established processes and the agility to create new ones.

This report presents recent work at SNL and shows our commitment to bringing in new materials and technologies to established procedures and ensure we can continue to provide photonic solutions to future needs.